Search Notes



Application No.	Applicant(s)	
10/600,393	CHEN ET AL.	
Examiner	Art Unit	
Toniae M Thomas	2822	Page 1

SEARCHED				
Class	Subclass	Date	Examiner	
438	275	9/10/2004	ТМТ	
**	770-777	9/10/2004	#	
**	787-788	9/10/2004	n	
99	791-792	9/10/2004	*	
438	981	9/10/2004	ТМТ	
updated	all above	3/18/2005	TMT	
updated	all above	7/11/2005	ТМТ	
438	199	7/11/2005	*	
**	706	7/11/2005	н	
*	710	7/11/2005	п	
n	723-724	7/11/2005	п	
н	745	7/11/2005	n	
Ħ	756-757	7/11/2005	**	

INTERFERENCE SEARCHED					
Class	Subclass	Date	Examiner		
438	all above	7/11/2005	TMT		
	·	_			
	•				

SEARCH NOT (INCLUDING SEARCH		)
	DATE	EXMR
USPAT US PG-Pub	9/10/2004	ТМТ
USPAT US PG-Pub	9/9/2004	TMT
USPAT US PG-Pub	9/8/2004	тмт
NPL database (silicon nitride and (atomic layer chemical vapor deposition or atomic layer deposition)	9/10/2004	тмт
NPL (silicon nitride and remote plasma enhanced chemical vapor deposition	9/10/2004	TMT
none	7/11/2005	ТМТ
,		